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## BIB DATA SHEET

CONFIRMATION NO. 7155

SERIAL NUMBER	FILING or 371(c) DATE	CLASS	GROUP ART UNIT	ATTORNEY DOCKET NO.	
10/587,394	07/27/2006 <b>RULE</b>	137	1792	294256US26PCT	
<b>APPLICANTS</b> Shuuiichi Ishizuka, Yamanashi, JAPAN; Masaru Sasaki, Hyogo, JAPAN; Tetsuro Takahashi, Yamanashi, JAPAN; Koji Maekawa, Yamanashi, JAPAN; <b>** CONTINUING DATA *****</b> This application is a 371 of PCT/JP05/01057 01/27/2005 <b>** FOREIGN APPLICATIONS *****</b> JAPAN 2004-020157 01/28/2004 <b>** IF REQUIRED, FOREIGN FILING LICENSE GRANTED **</b> 04/27/2007					
Foreign Priority claimed <input checked="" type="checkbox"/> Yes <input type="checkbox"/> No 35 USC 119(a-d) conditions met <input checked="" type="checkbox"/> Yes <input type="checkbox"/> No Verified and <u>/JOSEPH ALBERT</u> <u>MILLER, JR/</u> Acknowledged <u>Examiner's Signature</u>		<input type="checkbox"/> Met after Allowance <b>STATE OR COUNTRY</b> JAPAN	<b>SHEETS DRAWINGS</b> 7	<b>TOTAL CLAIMS</b> 20	<b>INDEPENDENT CLAIMS</b> 4
<b>ADDRESS</b> OBLON, SPIVAK, MCCLELLAND MAIER & NEUSTADT, P.C. 1940 DUKE STREET ALEXANDRIA, VA 22314 UNITED STATES					
<b>TITLE</b> Method for cleaning process chamber of substrate processing apparatus, substrate processing apparatus, and method for processing substrate					
<b>FILING FEE RECEIVED</b> 1100	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:		<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit		